

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Chen, et al	Conf. No.:	1057
Serial No.:	10/604,058	Art. Unit:	1763
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Title:	PLASMA PROCESSING MATERIAL RECLAMATION AND REUSE	Docket. No.:	FIS920030132US1 (IBMF-0018)

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

I. INTRODUCTORY COMMENTS

This paper is in response to the Office Action of 4 January 2007. Please amend the above-referenced patent application as follows:

The Amendments to the Claims are reflected in the listing of the claims that begins on page 2 of this paper.

Remarks begin on page 8 of this paper.

The Conclusion appears on page 10 of this paper.